# Monthly LabAdviser update: 2/6 2017

|  |  |  |
| --- | --- | --- |
| Updated Subject  | Contributor | Link to the updated pages |
|  |  |  |
| **ALD1**ALD of HfO2 now developed and tested on ALD1 | **Tanja Amport @danchip** | [ALD\_Picosun\_R200/Standard\_recipes\_on\_the\_ALD\_tool](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/Standard_recipes_on_the_ALD_tool)[ALD\_Picosun\_R200/HfO2\_deposition\_using\_ALD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/HfO2_deposition_using_ALD) |
| **Nanoimprint lithography**This page has been updated with the imprinter: “Imprinter 01” | **Rune K. Christiansen @danchip** | [NanoImprintLithography](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/NanoImprintLithography) |
| **Wet PolySi etch**Has been updated with the new wet bench | **Rune K. Christiansen @danchip** | [Wet\_Polysilicon\_Etch](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Wet_Polysilicon_Etch) |
| **Wafer Bonder 02**New page for “Wafer Bonder 02” | **Rune K. Christeansen @danchip** | [Bonding/Wafer\_Bonder\_02](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Bonding/Wafer_Bonder_02) |
| **RIE2: Si etch**Yannick has added results for the recipe OH\_PolyA at almost 100% load | **Yannick Seis @nbi.ku** | [Si\_etch\_using\_RIE1\_or\_RIE2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon/Si_etch_using_RIE1_or_RIE2) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

|  |
| --- |
|  |

|  |
| --- |
|  |
|  |
|  |

|  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |  |
| --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- |
|

|  |  |
| --- | --- |
|  | **Manual for MVD** |
|  | **Manual for Imprinter 1** |
|  | **Manual for resist strip** |
|  | **Manual for Spin coater: Labspin 02** |
|  | **Manual for Spin coater: Labspin 03** |
|  | **Manual for Wordentec** |
|  | **Manual for Physimeca** |
|  | **Manual for PECVD4** |
|  | **Manual for Isotropic Etch/Poly Etch** |
|  | **Manual for SEM Tabletop 1** |

 |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |
|  |  |